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Inventor Name Search Result

Your Search was:

Last Name = FUJIEDA

First Name = SHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 4
<u>09996417</u>	Not Issued	030	11/28/2001	IMAGE PROCESSING METHOD AND APPARATUS	FUJIEDA, SHIRO
<u>09974539</u>	Not Issued	030	10/09/2001	CONTOUR INSPECTION METHOD AND APPARATUS	FUJIEDA, SHIRO
<u>09445304</u>	Not Issued	071	12/06/1999	IMAGE PROCESSING APPARATUS AND METHOD, MEDIUM STORING PROGRAM FOR IMAGE PROCESSING, AND INSPECTION APPARATUS	FUJIEDA , SHIRO
<u>07988921</u>	Not Issued	164	03/12/1993	APPARATUS AND METHOD FOR DECIDING OR SETTING IDEAL LIGHTING CONDITIONS AND PHOTOGRAPHIC CONDITIONS, ETC., IN IMAGE PROCESSING SYSTEM, OR FOR AIDING IN DECIDING OR SETTING OF THE LIGHTING CONDITIONS	FUJIEDA , SHIRO

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Results:

 Journal or Magazine = **JNL** Conference = **CNF** Standard = **STD**
1 Dependence of Si pn junction perimeter leakage on the channel-stop dose and interlayer material
Fujieda, S.; Nobusawa, H.; Hamada, M.; Tanigawa, T.;

Electron Device Letters, IEEE , Volume: 20 Issue: 8 , Aug. 1999

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[\[Abstract\]](#) [\[PDF Full-Text \(56 KB\)\]](#) **IEEE JNL**
2 A new encapsulating method for semiconductor devices using resin
Ota, H.; Fujieda, S.; Okuyama, T.;

Electronic Components and Technology Conference, 1997. Proceedings., 47th May 1997

Page(s): 54 -59

[\[Abstract\]](#) [\[PDF Full-Text \(596 KB\)\]](#) **IEEE CNF**
3 Non-volatile FCG (ferroelectric-capacitor and transistor-gate connection) memory cell with non-destructive read-out operation
Kato, Y.; Fujieda, S.; Hayashi, Y.; Kunio, T.;

VLSI Technology, 1996. Digest of Technical Papers. 1996 Symposium on , 11-15 Oct. 1996

Page(s): 56 -57

[\[Abstract\]](#) [\[PDF Full-Text \(164 KB\)\]](#) **IEEE CNF**
4 A new encapsulating method for semiconductor devices using resin
Ota, H.; Fujieda, S.; Okuyama, T.; Yoshizumi, A.;

Electronic Manufacturing Technology Symposium, 1995, Proceedings of 1995 International, 18th IEEE/CPMT International , 4-6 Dec. 1995

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[\[Abstract\]](#) [\[PDF Full-Text \(340 KB\)\]](#) **IEEE CNF**